



INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				<b>Complete if Known</b>	
Sheet		of		Application Number	10/632,698
				Filing Date	August 1, 2003
				First Named Inventor	Bevan Staple
				Art Unit	1762
				Examiner Name	Not yet known
				Attorney Docket Number	019930-002310US

<b>U.S. PATENT DOCUMENTS+</b>					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code <sup>3</sup> (if known)		
AA	US-				
AB	US-				

<b>FOREIGN PATENT DOCUMENTS</b>						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	
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AC						<input type="checkbox"/>
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<b>NON PATENT LITERATURE DOCUMENTS</b>						
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.				
<i>BJ</i>	AE	ARK-CHEW WONG, JOHN R. CLARK and CLARK T.-C. NGUYEN, Anneal-Activated, Tunable 68 MHz Micromechanical Filters, Center for Integrated Microsystems, Dept. of Electrical and Computer Science, University of Michigan, Ann Arbor, Michigan 48109, Transducers '99, June 7-10, 1999, pp. 1390-1393, Sendai, Japan				<input type="checkbox"/> <sup>T<sup>2</sup></sup>
<i> </i>	AF	ASHUF, C.M.A., et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74, June 1999, pp. 118-122				<input type="checkbox"/>
<i> </i>	AG	TORCHEUX, L., et al., "Electrochemical Coupling Effects on the corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 6 June 1995, pp. 2037-2046.				<input type="checkbox"/>
<i> </i>	AH	KELLER, CHRISTOPHER GUILD, "Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion," dissertation submitted in the graduate division of the University of California, Berkeley, Fall 1998.				<input type="checkbox"/>
<i>BJ</i>	AI	MULLER, LILAC, "Gimballed Electrostatic-Microactuators with Embedded Interconnects," dissertation submitted in the graduate division of the University of California, Berkeley, Spring 2000.				<input type="checkbox"/>

Examiner Signature	<i>B. Talbot</i>	Date Considered	<i>5/11/05</i>
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.